

EV Group announces multi-functional micro- and nanoimprint solution 'EVG7300' - January 19, 2022

EVG introduced the EVG®7300 automated SmartNIL® nanoimprint and wafer-level optics system. The EVG7300 is the company's most advanced solution to combine multiple UV-based process capabilities, such as nanoimprint lithography (NIL), lens molding and lens stacking (UV bonding), in a single platform. Supporting wafer sizes up to 300 mm and featuring high-precision alignment, advanced process control and high throughput, the EVG7300 meets the high-volume manufacturing needs for a variety of freeform and high-precision nano- and micro-optical components and devices. The system features industry-leading alignment accuracy (down to 300 nm), which is enabled by a combination of alignment stage improvements, high-accuracy optics, multi-point gap control, non-contact gap measurement and multi-point force control.



http://www.denews.co.kr/news/articleView.html?idxno=22363